

Labs work @ Phelma

PHELMA 4PMTMNL2 TP: Micro and Nanosystems (4 ECTS)

- Objectives
- Organization
 - Study logic
 - •Breakdown structure
 - Schedule
 - •Where? When?
- Assessment

40h / student

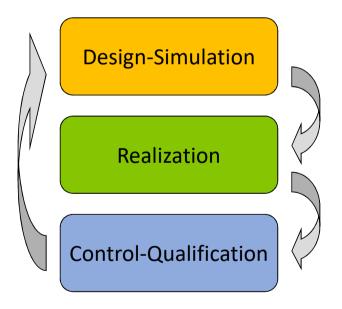
12 professors involved

Technical support from CIME Nanotech

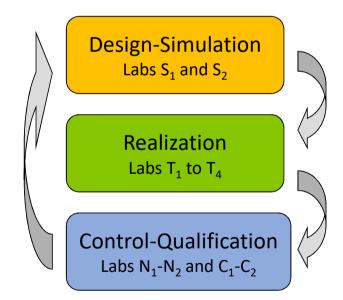


Objectives

Device manufacturing flow

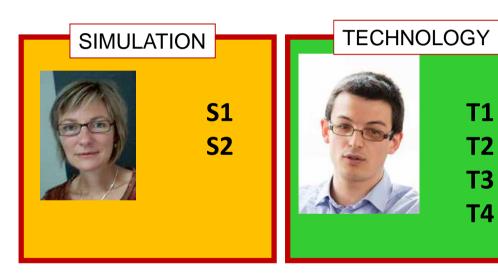


Lab-work organization

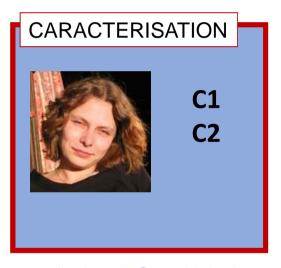




Organization







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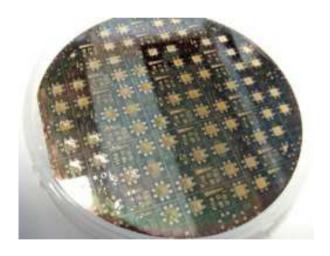


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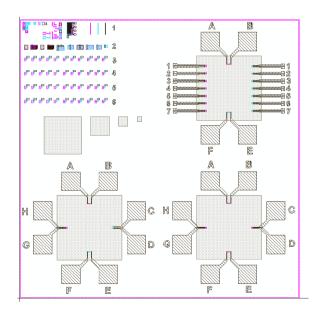
All for one chip, one chip for all

• Wafers:



- 4-inches Si
- MOS tr. and MEMS

• Chip layout:



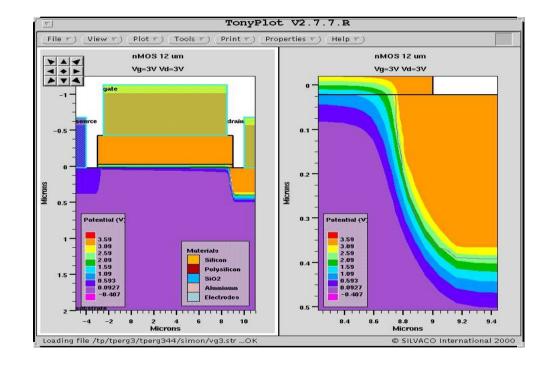


S₁-S₂: Simulation sessions

- S₁: technological simulation Athena software
- S₂: electrical simulation
 Atlas software



Anne Kaminski anne.kaminski@grenoble-inp.fr





T₁-T₄: Clean-room sessions

Work in a clean room:



- Dedicated suits
- Trousers and T-shirt
- Strict respect of the safety procedures
- Bring an USB memory stick

• MEMS-CMOS proc. flow:



 Double-side photolithography, deep RIE, ion implantation, oxidation, etc...



D. Bucci



L. Montes



M. Bawedin



JE. Broquin



A. Kaminski



A. Kuhn

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Clean room is a chemistry environment so:

- covered arms and legs, covered stable shoes, no make-up, no jewels, no loose hair... and anything that is not compatible with a clean room suit.
- No contact lenses.
- Do not touch your face with your gloves!
- Strictly follow the security procedure explained by your teacher at the beginning of the session.
- If you pick up a red telephone, DO NOT hang up by yourself, tell the security guy it is a mistake and wait him to tell you to hang up.



C₁-C₂: Characterization sessions

• C₁₋₂: CMOS characterization





Maryline BAWEDIN



Théano KARATSORI

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Standard industrial measurements

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N1-N2: Nanoworld sessions



T. Quisse





J. Coraux



F. Marchi



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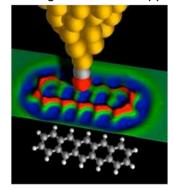
"Scanning Probe Microscopy"

Description: Learn and understand different scanning probe microscopy methods for local inspection of surfaces and devices.

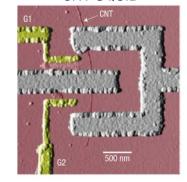
Why this course in the Nanotech training? SPM essential ingredient an Nanotechnology and Nanoscience, visualizing nano-objects, but also for manipulating them.

Linked with Advanced Microscopy lecture

AFM single molecule mapping



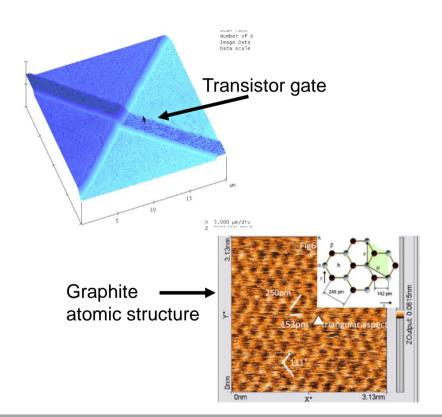
CNT SQUID



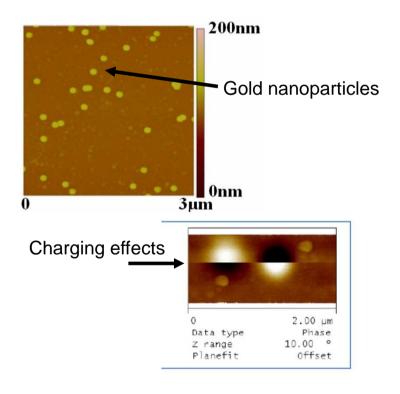


N1-N2: Nanoworld sessions

N₁: STM, contact mode AFM



N₂: Tapping mode AFM, EFM





Timetable

First session: February 5th am

			G1		G2		G3		G4		G5		G6		G7		G8		G9		G10		MaJ	27/01/2020	
Mod	05/02/20	AM	N1	SLD	O2		03		04		S1	AK	S1	AK	S1	AK	S1	AK	03		010		Mao	2170172020	-
Wed Wed	05/02/20	PM	S1	AK	S1	AK	S1	AK	S1	AK	N1	CW	51	AK	51	AK	51	AK							-
Thurs	06/02/20	PM	S2	AK	S2	AK	S2	AK	S2	AK	N2	TO											Prenom	Nom	Code
Wed	12/02/20	AM	T1	DB	T1	JEB	N1	CW	-		S2	AK	S2	AK	S2	AK	S2	AK					Simon	Le Denmat	SLD
Wed	12/02/20	PM	T2 DB T2 JEB N2 TO Communication at work														Marylin	Bawedin	MB						
Thurs	13/02/20	PM	N2	SLD							С	omm	unica	tion	at wo	rk							Davide	Bucci	DB
Wed	19/02/20	AM	T3	DB	T3	JEB					С	omm	unica							Pro	ject		Clemens	Winkelmann	CW
Wed	19/02/20	PM	T4	DB	T4	JEB								Pro	ject								Anne	Kaminski	AK
Wed	04/03/20	AM	C1	MB	C2	MB	T1	JEB	T1	LM					N2	SLD			S1	AK	S1	AK	Laurent	Montes	LM
Wed	04/03/20	PM	C2	МВ	C1	МВ	T2	JEB	T2	LM					N1	FM			S2	AK	S2	AK	JE	Broquin	JEB
Thurs	05/03/20	PM			N1	FM																	Johann	Coraux	JC
Wed	11/03/20	AM	Communication at work								T1	MB	T1	JEB			N1	SLD	Com	muni	cation	at w	Florence	Marchi	FM
Wed	11/03/20	PM	Project								T2	MB	T2	JEB			N2	JC		Pro	ject		Thierry	Ouisse	ТО
Wed	18/03/20	AM	Project T3 AK						Т3	LM	Project								N1	CW	Pro	ject	Theano	Karatsori	TK
Wed	18/03/20	PM	N2 TO T4 AK						T4	LM	Project														
Thurs	19/03/20	PM	Communication at work						N1										omm	unica	tion a	t wor			
Wed	25/03/20	AM	C1 TK				C2	TK	Т3	T3 AK T3 DB Project						N2	JC	Pro	ject						
Wed	25/03/20	PM		Pro	ject		C2	TK	C1	TK	T4	AK	T4	DB				Pro	oject						
Wed	01/04/20	AM	Project						Communication at work										T1	AK	T1	JEB			
Wed	01/04/20	PM	Project						N2	SLD	Project							T2	AK	T2	JEB				
Wed	08/04/20	AM	Project								C1	TK	C2	TK		Pro	ject		Т3	МВ	T3	JEB			
Wed	08/04/20	PM	Project								C2	TK	C1	TK		Pro	ject		T4	МВ	T4	JEB			
Wed	29/04/20	AM	Project										N1	CW	T1	AK	T1	JEB	C1	TK	C2	TK			
Wed	29/04/20	PM	Project N2 JC T2												T2	AK	T2	JEB	C2	TK	C1	TK			
Wed	06/05/20	AM	С	ommi	unica	tion a	at wo	rk	Project						T3	МВ	T3	JEB	omm	unica	tion a	t wor			
Wed	06/05/20	PM									Pro	ojet		T4 M			T4	JEB			N2	JC			
Thurs	07/05/20	AM									С	omm	unica	ication at work											
Thurs	07/05/20	PM	С	ommi	unica	tion a	at wo	rk							C1	TK	C2	TK	omm	unica	tion a	t wor			
Wed	13/05/20	AM													C2	TK	C1	TK			N1	CW			
Wed	13/05/20	PM	С	ommi	unica	tion a	at wo	rk											omm	unica	tion a	t wor			



Where and when?

- S₁-S₂: e. hall BCA-I building
- T₁-T₄: e. hall BCA-I building
- N₁-N₂: e. hall BCA-I building
- C₁-C₂: e. hall BCA-I building



ALL: 8 AM or 13 PM, BE ON TIME!

Attendance mandatory.... impossible to redo or shift the practical



Documents: chamilo

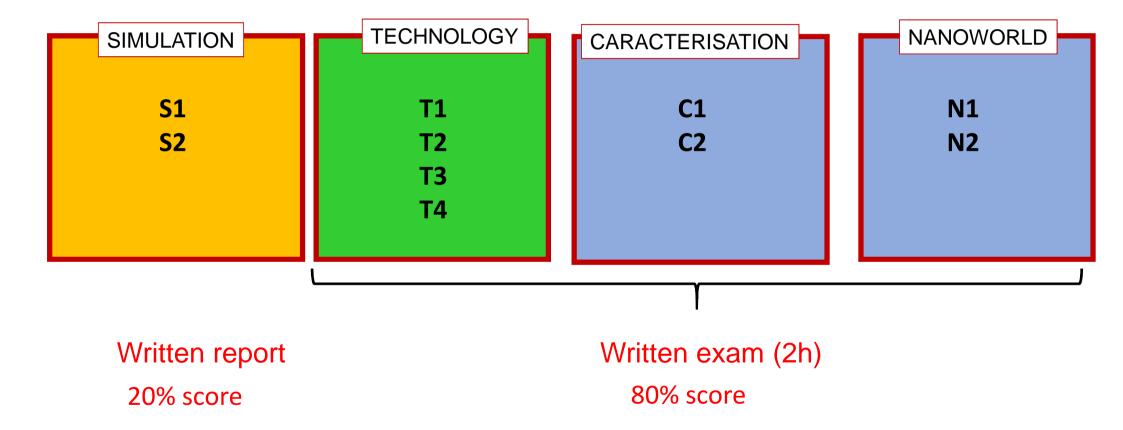
PHELMA 4PMTMNL2 TP: Micro and Nanosystems

- Clean room (T1-T4)
 - Questions about the process flow
 - Process flow slides
 - Wafer page

- C, S and N:
 - C1-C2
 - S1-S2
 - N1-N2



Assessment





Conclusion

- Four categories of labs in CIME-MINATEC:
 - Simulation
 - Technology
 - Characterization
 - Nanoworld



- Documents on Chamilo
- State-of-the-art tools and procedures
- One contact person assigned per lab type
- In case of problems, warn us in time!

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